PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1
Stylesheet Version v1.2

EPAS ID: PAT3231473

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

CONVEYING PARTY DATA

Name	Execution Date
TOKYO ELECTRON LIMITED	01/13/2015

RECEIVING PARTY DATA

Name:	KLA-TENCOR CORPORATION
Street Address:	ONE TECHNOLOGY DRIVE
City:	MILPITAS
State/Country:	CALIFORNIA
Postal Code:	95035

PROPERTY NUMBERS Total: 57

Property Type	Number
Patent Number:	8108328
Application Number:	12193341
Patent Number:	8195435
Patent Number:	8560270
Patent Number:	8666703
PCT Number:	US2011044394
Application Number:	12775392
PCT Number:	US2011034833
Patent Number:	8452718
Application Number:	12785310
PCT Number:	US2011037030
Application Number:	12900863
PCT Number:	US2011055163
Patent Number:	8577820
Application Number:	14044729
PCT Number:	US2012026927
Patent Number:	8381140
PCT Number:	US2012024477
Application Number:	13164398
PCT Number:	US2012042437

Property Type	Number
Patent Number:	8762100
Patent Number:	8670948
PCT Number:	US2012070675
Application Number:	13286079
PCT Number:	US2012062234
Application Number:	13610613
PCT Number:	US2012068786
Application Number:	61576817
Application Number:	13712734
PCT Number:	US2012069910
Application Number:	61576825
Application Number:	13781474
PCT Number:	US2013030907
Application Number:	61616971
Application Number:	61642913
Application Number:	13889655
Application Number:	61644147
Application Number:	14068789
Application Number:	61720930
Application Number:	14170150
PCT Number:	US2014014680
Application Number:	61761146
Application Number:	14293221
PCT Number:	US2014040639
Application Number:	61830533
Application Number:	61831080
Application Number:	14294540
Application Number:	61830536
Application Number:	14293625
PCT Number:	US2014040643
Application Number:	61830543
Application Number:	14293809
PCT Number:	US2014040644
Application Number:	61831085
Application Number:	61830546
Application Number:	14542546
Application Number:	61904625

CORRESPONDENCE DATA

Fax Number:

Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.

Phone:	503.439.8778
Email:	Andrea_Dolder@BSTZ.com
Correspondent Name:	MARK C. VAN NESS
Address Line 1:	1925 NW AMBERGLEN PARKWAY
Address Line 2:	SUITE 230
Address Line 4:	BEAVERTON, OREGON 97006

ATTORNEY DOCKET NUMBER:	8536P*
NAME OF SUBMITTER:	MARK C. VAN NESS
SIGNATURE:	/Mark C. Van Ness/
DATE SIGNED:	02/18/2015

Total Attachments: 27

source=assignments#page1.tif
source=assignments#page2.tif
source=assignments#page3.tif
source=assignments#page4.tif
source=assignments#page5.tif
source=assignments#page6.tif
source=assignments#page7.tif
source=assignments#page8.tif
source=assignments#page9.tif
source=assignments#page10.tif
source=assignments#page11.tif
source=assignments#page12.tif
source=assignments#page13.tif
source=assignments#page14.tif
source=assignments#page15.tif
source=assignments#page16.tif
source=assignments#page17.tif
source=assignments#page18.tif
source=assignments#page19.tif
source=assignments#page20.tif
source=assignments#page21.tif
source=assignments#page22.tif
source=assignments#page23.tif
source=assignments#page24.tif
source=assignments#page25.tif
source=assignments#page26.tif
source=assignments#page27.tif

Schedule 7.2
Assignment Forms

ASSIGNMENT OF PATENT RIGHTS

For good and valuable consideration, the receipt of which is hereby acknowledged, Tokyo Electron Limited ("***Assignor***"), does hereby sell, assign, transfer, and convey unto KLA-Tencor Corporation ("***Assignee***"), all of Assignor's right, title, and interest in and to the following (collectively, the "***Assigned Patent Rights***"):

(a) the patents and patent applications listed in the table attached hereto (the "***Patents***");

(b) any future reissues, reexaminations, extensions, continuations, continuations-in-part, continuing prosecution application, foreign counterparts, requests for continuing examinations, divisions, and registrations of any of the Patents, and any patent or patent application claiming, in whole or in part, benefit of a common filing date with any of the foregoing;

(c) rights to apply in any or all countries of the world for future patents, certificates of invention, utility models, industrial design protections, design patent protections, or other future governmental grants or issuances of any type related to the Patents; and

(d) causes of action and enforcement rights of any kind under, or on account of, any of the Patents and/or any of the items described in either of the foregoing categories (b) or (c), including, without limitation, all causes of action, enforcement rights and all other rights to seek and obtain any other remedies of any kind for past, current and future infringement.

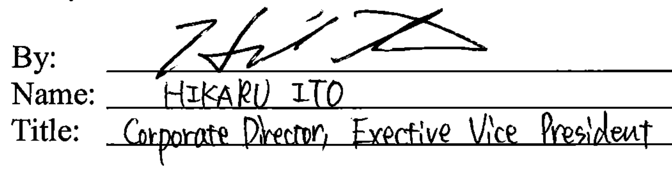
Assignor hereby authorizes the respective patent office or governmental agency in each jurisdiction to issue any and all future patents, certificates of invention, utility models or other governmental grants or issuances that may be granted upon any of the Assigned Patent Rights in the name of Assignee, as the assignee to the entire interest therein. This Assignment of Patent Rights will inure for the benefit of any permitted successors or assigns of Assignee.

Assignor will, at the commercially reasonable request of Assignee, cause each of Assignor's Affiliates to sign the reasonably necessary or appropriate documents, provide the reasonably necessary or appropriate testimony and, in general, do the commercially reasonable, appropriate and lawful things reasonably requested of such Assignor by the Assignee to carry out and fulfill the purposes and intent of this agreement.

IN WITNESS WHEREOF this Assignment of Patent Rights is executed on January 13, 2015.

ASSIGNOR:

Tokyo Electron Limited



By: ______________________
Name: HIKARU ITO
Title: Corporate Director, Exective Vice President

46108235_2

ATTACHMENT TO ASSIGNMENT OF PATENT RIGHTS

The following patents and patent applications, along with any reissues, reexaminations, extensions, continuations, continuations-in-part, continuing prosecution application, foreign counterparts, requests for continuing examinations, divisions, and registrations of any of the patents or patent applications, and any patent or patent application claiming, in whole or in part, benefit of a common filing date with any of the foregoing:

S. NO	BSTZ File Number	Client REF NO.	Date Filed	App. NO	Title	Pub. NO	Pub. Date	Patent NO.	Issue Date	Status
1	8536P001	FIJI-001; P2932	7/17/08	12/175,271	NEURAL NETWORK BASED HERMITE INTERPOLATOR FOR SCATTEROMETRY PARAMETER ESTIMATION	US-2010-0017351-A1	1/21/10	8,108,328	1/31/12	Issued
2	8536P002	FIJI-002; P2933	8/18/08	12/193,341	COMPUTATION EFFICIENCY BY DIFFRACTION ORDER TRUNCATION	US-2010-0042388-A1	2/18/10			Pending
3	8536P003	TEL Ref.: FIJI-003; KLA Ref.: P3566	12/19/08	12/340,421	HYBRID DIFFRACTION MODELING OF DIFFRACTING STRUCTURES (FIJI-003)	US-2010-0157315-A1	6/24/10	8,195,435	6/5/12	Issued

46108235_2

4	8536P004	FIJI-008; P3578	12/9/08	12/331,192	RATIONAL APPROXIMATION AND CONTINUED-FRACTION APPROXIMATION APPROACHES FOR COMPUTATION EFFICIENCY OF DIFFRACTION SIGNALS	US-2010-0145655-A1	6/10/10	8,560,270	10/15/13	Issued
5	8536P005	FIJI-012; P3580	7/22/10	12/841,932	METHOD FOR AUTOMATED DETERMINATION OF AN OPTIMALLY PARAMETERIZED SCATTEROMETRY MODEL	US-2012-0022836-A1		8,666,703	3/4/14	Issued
6	8536P005CN	TEL Ref.: FIJI-012CN; KLA Ref.: P3580CN	7/18/11	201180032548.9	METHOD FOR AUTOMATED DETERMINATION OF AN OPTIMALLY PARAMETERIZED SCATTEROMETRY MODEL	CN 103026204 A	4/3/13			Pending
7	8536P005EP	TEL Ref.: FIJI-012EP; KLA Ref.: P3580EP	7/18/11	11810230.0	METHOD FOR AUTOMATED DETERMINATION OF AN OPTIMALLY PARAMETERIZED SCATTEROMETRY	2596334	5/29/13			Pending

46108235_2

					MODEL					
8	8536P005JP	TEL Ref.: FIJI-012JP - KLA Ref.: P3580JP	7/18/11	2013-520784	METHOD FOR AUTOMATED DETERMINATION OF AN OPTIMALLY PARAMETERIZED SCATTEROMETRY MODEL					Pending
9	8536P005KR	TEL Ref.: FIJI-012KR - KLA Ref.: P3580KR	7/18/11	10-2012-7034413	METHOD FOR AUTOMATED DETERMINATION OF AN OPTIMALLY PARAMETERIZED SCATTEROMETRY MODEL					Pending
10	8536P005PCT	TEL Ref.: FIJI-012PCT; KLA Ref.: P3580PCT	7/18/11	PCT/US2011/044394	METHOD FOR AUTOMATED DETERMINATION OF AN OPTIMALLY PARAMETERIZED SCATTEROMETRY MODEL	WO 2012/012345				Pending
11	8536P005TW	FIJI-012TW; P3580TW	7/21/11	100125861	METHOD FOR AUTOMATED DETERMINATION OF AN OPTIMALLY PARAMETERIZED SCATTEROMETRY	201211789	3/16/12			Pending

46108235_2

					MODEL					
12	8536P006	FIJI-013; P3565	5/6/10	12/775,392	DETERMINATION OF MATERIAL OPTICAL PROPERTIES FOR OPTICAL METROLOGY OF STRUCTURES	US-2011-0276319-A1				Pending
13	8536P006CN	FIJI-013CN; P3565CN	5/2/11	201180022825.8	DETERMINATION OF MATERIAL OPTICAL PROPERTIES FOR OPTICAL METROLOGY OF STRUCTURES	CN 103003681 A	3/27/13			Pending
14	8536P006EP	FIJI-013EP; P3565EP	5/2/11	11778115.3	DETERMINATION OF MATERIAL OPTICAL PROPERTIES FOR OPTICAL METROLOGY OF STRUCTURES	2567209	3/13/13			Pending
15	8536P006JP	FIJI-013JP; P3565JP	5/2/11	2013-509147	DETERMINATION OF MATERIAL OPTICAL PROPERTIES FOR OPTICAL METROLOGY OF					Pending

46108235_2

					STRUCTURES					
16	8536P006K R	FIJI-013KR; P3565KR	5/2/11	10-2012-7031766	DETERMINATION OF MATERIAL OPTICAL PROPERTIES FOR OPTICAL METROLOGY OF STRUCTURES					Pending
17	8536P006P CT	FIJI-013WO; KLA P3565	5/2/11	PCT/US2011 /034833	DETERMINATION OF MATERIAL OPTICAL PROPERTIES FOR OPTICAL METROLOGY OF STRUCTURES	WO 2011/139982				Pending
18	8536P007	FIJI-015; P3567	6/10/10	12/813,431	DETERMINATION OF TRAINING SET SIZE FOR A MACHINE LEARNING SYSTEM	US-2011-0307424-A1		8,452,718	41422	Issued
19	8536P009	FIJI-016; P3579	5/21/10	12/785,310	COMPUTATION EFFICIENCY BY ITERATIVE SPATIAL HARMONICS ORDER TRUNCATION	US-2011-0288822-A1				Pending

20	8536P009CN	FIJI-016CN:P3579CN	5/18/11	201180025313.7	COMPUTATION EFFICIENCY BY ITERATIVE SPATIAL HARMONICS ORDER TRUNCATION	CN 102947732 A	2/27/13			Pending
21	8536P009EP	FIJI-016EP:P3579EP	5/18/11	11784190.8	COMPUTATION EFFICIENCY BY ITERATIVE SPATIAL HARMONICS ORDER TRUNCATION	2572304	3/27/13			Pending
22	8536P009JP	FIJI-016JP:P3579JP	5/18/11	2013-512086	COMPUTATION EFFICIENCY BY ITERATIVE SPATIAL HARMONICS ORDER TRUNCATION					Pending
23	8536P009KR	FIJI-016KR:P3579KR	5/18/11	10-2012-7033551	COMPUTATION EFFICIENCY BY ITERATIVE SPATIAL HARMONICS ORDER TRUNCATION					Pending
24	8536P009PCT	FIJI-016PCT; KLA P3579PCT	5/18/11	PCT/US2011/037030	COMPUTATION EFFICIENCY BY ITERATIVE SPATIAL HARMONICS ORDER	WO 2011/146643				Pending

					TRUNCATION					
25	8536P010	FIJI-017; P3589	10/8/10	12/900,863	METHOD OF DETERMINING AN ASYMMETRIC PROPERTY OF A STRUCTURE	US-2012-0086940-A1				Pending
26	8536P010CN	FIJI-017CN; P3589CN	10/6/11	201180048788.8	METHOD OF DETERMINING AN ASYMMETRIC PROPERTY OF A STRUCTURE	CN 103154664 A	6/12/13			Pending
27	8536P010EP	FIJI-017EP; P3589EP	10/6/11	11831632.2	METHOD OF DETERMINING AN ASYMMETRIC PROPERTY OF A STRUCTURE	2625487	8/14/13			Pending
28	8536P010JP	FIJI-017JP; P3589JP	10/6/11	2013-532956	METHOD OF DETERMINING AN ASYMMETRIC PROPERTY OF A STRUCTURE					Pending
29	8536P010KR	FIJI-017KR; P3589KR	10/6/11	10-2013-7010841	METHOD OF DETERMINING AN ASYMMETRIC PROPERTY OF A STRUCTURE					Pending

30	8536P010P CT	FIJI-017PCT; KLA P3589PCT	10/6/11	PCT/US2011 /055163	METHOD OF DETERMINING AN ASYMMETRIC PROPERTY OF A STRUCTURE	WO 2012/048156				Pending
31	8536P011	FIJI-019; P3619	3/4/11	13/041,253	ACCURATE AND FAST NEURAL NETWORK TRAINING FOR LIBRARY-BASED CRITICAL DIMENSION (CD) METROLOGY	US-2012-0226644-A1		8,577,820	41583	Issued
32	8536P011C	FIJI-019C_P3619C	10/2/13	14/044,729	ACCURATE AND FAST NEURAL NETWORK TRAINING FOR LIBRARY-BASED CRITICAL DIMENSION (CD) METROLOGY	US-2014-0032463-A1				Pending
33	8536P011C N	FIJI-109CN: P3619CN	2/28/12	2012800109 87.4	ACCURATE AND FAST NEURAL NETWORK TRAINING FOR LIBRARY-BASED CRITICAL DIMENSION (CD) METROLOGY	CN 103403724A	11/20/13			Pending

46108235_2

34	8536P011EP	FIJI-019EP:P3619EP	2/28/12	12779511.0	ACCURATE AND FAST NEURAL NETWORK TRAINING FOR LIBRARY-BASED CRITICAL DIMENSION (CD) METROLOGY	2681684	1/8/14			Pending
35	8536P011JP	FIJI-109JP:P3619JP	2/28/12	2013-556799	ACCURATE AND FAST NEURAL NETWORK TRAINING FOR LIBRARY-BASED CRITICAL DIMENSION (CD) METROLOGY					Pending
36	8536P011KR	FIJI-019KR: P3619KR	2/28/12	10-2013-7026272	ACCURATE AND FAST NEURAL NETWORK TRAINING FOR LIBRARY-BASED CRITICAL DIMENSION (CD) METROLOGY					Pending
37	8536P011PCT	FIJI-019PCT: P3619PCT	2/28/12	PCT/US2012/026927	ACCURATE AND FAST NEURAL NETWORK TRAINING FOR LIBRARY-BASED CRITICAL DIMENSION (CD)	WO 2012/150993				Pending

					METROLOGY					
38	8536P011TW	FIJI-019TW: P3619TW	3/1/12	101/106806	ACCURATE AND FAST NEURAL NETWORK TRAINING FOR LIBRARY-BASED CRITICAL DIMENSION (CD) METROLOGY	201243738	11/1/12			Pending
39	8536P012	FIJI-020; P3651	2/11/11	13/025,654	WIDE PROCESS RANGE LIBRARY FOR METROLOGY	US-2012-0210289-A1		8,381,140	41324	Issued
40	8536P012CN	FIJI-020CN: P3651CN	2/9/12	201280008607.3	WIDE PROCESS RANGE LIBRARY FOR METROLOGYWIDE PROCESS RANGE LIBRARY FOR METROLOGY	CN103443900A	12/11/13			Pending
41	8536P012EP	FIJI-020EP: P3651EP	2/9/12	12744611.0	WIDE PROCESS RANGE LIBRARY FOR METROLOGYWIDE PROCESS RANGE LIBRARY FOR METROLOGY	2673797	12/18/13			Pending

42	8536P012JP	FIJI-020JP: P3651JP	2/9/12	2013-553563	WIDE PROCESS RANGE LIBRARY FOR METROLOGYWIDE PROCESS RANGE LIBRARY FOR METROLOGY					Pending
43	8536P012KR	FIJI-020KR: P3651KR	2/9/12	10-2013-7023309	WIDE PROCESS RANGE LIBRARY FOR METROLOGYWIDE PROCESS RANGE LIBRARY FOR METROLOGY					Pending
44	8536P012PCT	FIJI-020PCT: P3651PCT	2/9/12	PCT/US2012/024477	WIDE PROCESS RANGE LIBRARY FOR METROLOGY	WO 2012/109441				Pending
45	8536P012TW	FIJI-020TW: P3651TW	2/10/12	101104442	WIDE PROCESS RANGE LIBRARY FOR METROLOGY	201241400	10/16/12			Pending
46	8536P013	FIJI-021; P3604	6/20/11	13/164,398	METHOD OF OPTIMIZING AN OPTICAL PARAMETRIC MODEL FOR STRUCTURAL ANALYSIS USING OPTICAL CRITICAL DIMENSION (OCD)	US-2012-0323356-A1				Pending

46108235_2

					METROLOGY					
47	8536P013P CT	FIJI-021PCT; P3604PCT	6/14/12	PCT/US2012 /042437	METHOD OF OPTIMIZING AN OPTICAL PARAMETRIC MODEL FOR STRUCTURAL ANALYSIS USING OPTICAL CRITICAL DIMENSION (OCD) METROLOGY	WO 2012/177477				Pending
48	8536P013T W	FIJI-021TW; P3604TW	6/15/12	101121678	METHOD OF OPTIMIZING AN OPTICAL PARAMETRIC MODEL FOR STRUCTURAL ANALYSIS USING OPTICAL CRITICAL DIMENSION (OCD) METROLOGY	201314174	4/1/13			Pending
49	8536P014	FIJI-023; P3842	2/10/12	13/371,317	NUMERICAL APERTURE INTEGRATION FOR OPTICAL CRITICAL DIMENSION (OCD) METROLOGY			8,762,100	41814	Issued

46108235_2

50	8536P014C	TEL Ref.: FIJI-P023C; KLA Ref.: P3842C	10/19/12	13/656,487	NUMERICAL APERTURE INTEGRATION FOR OPTICAL CRITICAL DIMENSION (OCD) METROLOGY	US-2013-0211760-A1		8,670,948	41709	Issued
51	8536P014C EP	TEL Ref.: FIJI-023CEP; KLA Ref.: P3842CEP	12/19/12	12868261.4	NUMERICAL APERTURE INTEGRATION FOR OPTICAL CRITICAL DIMENSION (OCD) METROLOGY					Pending
52	8536P014C KR	FIJI-023CKR; P3842CKR	12/19/12	10-2014-7025250	NUMERICAL APERTURE INTEGRATION FOR OPTICAL CRITICAL DIMENSION (OCD) METROLOGY					Pending
53	8536P014C PCT	TEL Ref.: FIJI-P023CPCT; KLA Ref.: P3842CPCT	12/19/12	PCT/US2012/070675	NUMERICAL APERTURE INTEGRATION FOR OPTICAL CRITICAL DIMENSION (OCD) METROLOGY	WO 2013/119324				Pending
54	8536P015	FIJI-024; P3753	10/31/11	13/286,079	PROCESS VARIATION-BASED MODEL OPTIMIZATION FOR METROLOGY	US-2013-0110477-A1				Pending

46108235_2

55	8536P015CN	FIJI-024CN P3753CN	10/26/12	201280053873.8	PROCESS VARIATION-BASED MODEL OPTIMIZATION FOR METROLOGY	CN104025275 A	9/3/14			Pending
56	8536P015EP	FIJI-024EP P3753EP	10/26/12	12846765.1	PROCESS VARIATION-BASED MODEL OPTIMIZATION FOR METROLOGY	2775175	9/10/14			Pending
57	8536P015JP	FIJI-024JP P3753JP	10/26/12	2014-539075	PROCESS VARIATION-BASED MODEL OPTIMIZATION FOR METROLOGY					Pending
58	8536P015KR	FIJI-024KR P3753KR	10/26/12	10-2014-7014441	PROCESS VARIATION-BASED MODEL OPTIMIZATION FOR METROLOGY					Pending
59	8536P015PCT	FIJI-024PCT:P3753PCT	10/26/12	PCT/US2012/062234	PROCESS VARIATION-BASED MODEL OPTIMIZATION FOR METROLOGY	WO 2013/066767				Pending
60	8536P015TW	FIJI-024TW:P3753TW	10/30/12	101140191	PROCESS VARIATION-BASED MODEL OPTIMIZATION FOR	201329417	7/16/13			Pending

46108235_2

					METROLOGY					
61	8536P016	FIJI-026; P3729	9/11/12	13/610,613	LIBRARY GENERATION WITH DERIVATIVES IN OPTICAL METROLOGY	US-2013-0158957-A1				Pending
62	8536P016EP	FIJI-026EP P3729EP	12/10/12	12856976.1	LIBRARY GENERATION WITH DERIVATIVES IN OPTICAL METROLOGY	2791968	10/22/14			Pending
63	8536P016KR	FIJI-026KR P3729KR	12/10/12	10-2014-7019881	LIBRARY GENERATION WITH DERIVATIVES IN OPTICAL METROLOGY					Pending
64	8536P016PCT	FIJI-026PCT:P3729PCT	12/10/12	PCT/US2012/068786	LIBRARY GENERATION WITH DERIVATIVES IN OPTICAL METROLOGY	WO 2013/090200				Pending
65	8536P016TW	FIJI-026TW:P3729TW	12/14/12	101147673	LIBRARY GENERATION WITH DERIVATIVES IN OPTICAL METROLOGY	201331548	8/1/13			Pending

66	8536P016Z	FIJI-026Z:P3729Z	12/16/11	61/576,817	LIBRARY GENERATION WITH DERIVATIVES IN OPTICAL METROLOGY					Expired
67	8536P017	FIJI-025, P3740	12/12/12	13/712,734	HYBRID DERIVATIVES IN OPTICAL SCATTEROMETRY	US-2013-0158948-A1				Pending
68	8536P017EP	FIJI-025EP; P3740EP	12/14/12	12857471.2	TECHNIQUES FOR OPTIMIZED SCATTEROMETRY	2791653	10/22/14			Pending
69	8536P017KR	FIJI-025KR; P3740KR	12/14/12	10-2014-7019875	TECHNIQUES FOR OPTIMIZED SCATTEROMETRY					Pending
70	8536P017PCT	FIJI-025PCT, P3740PCT	12/14/12	PCT/US2012/069910	TECHNIQUES FOR OPTIMIZED SCATTEROMETRY	WO 2013/090816				Pending
71	8536P017Z	FIJI-025; P3740	12/16/11	61/576,825	HYBRID DERIVATIVES IN OPTICAL SCATTEROMETRY					Expired
72	8536P018	FIJI-027_P3788	2/28/13	13/781,474	MODEL OPTIMIZATION APPROACH BASED ON SPECTRAL SENSITIVITY	US-2013-0262044-A1				Pending

46108235_2

73	8536P018EP	FIJI-027EP_P3788EP	3/13/13	13768674.7	MODEL OPTIMIZATION METHOD BASED ON SPECTRAL SENSITIVITY					Pending
74	8536P018JP	FIJI-027JP_P3788JP	3/13/13		MODEL OPTIMIZATION METHOD BASED ON SPECTRAL SENSITIVITY					Pending
75	8536P018KR	FIJI-027KR_P3788KR	3/13/13	10-2014-7029649	MODEL OPTIMIZATION METHOD BASED ON SPECTRAL SENSITIVITY					Pending
76	8536P018PCT	FIJI-027PCT_P3788PCT	3/13/13	PCT/US2013/030907	MODEL OPTIMIZATION METHOD BASED ON SPECTRAL SENSITIVITY	WO 2013/148203				Pending
77	8536P018TW	FIJI-027TW_P3788TW	3/28/13	102111257	MODEL OPTIMIZATION METHOD BASED ON SPECTRAL SENSITIVITY	201346214	11/16/13			Pending
78	8536P018Z	FIJI-027PROV; P3788PROV	3/28/12	61/616,971	MODEL OPTIMIZATION METHOD BASED ON SPECTRAL					Expired

46108235_2

					SENSITIVITY					
79	8536P019Z	FIJI-029; P3880	5/4/12	61/642,913	ADAPTIVE FIELD INTEGRATION SETUP FOR 3D SCATTEROMETRY					Expired
80	8536P020	FIJI Ref.: FIJI-028; KLA Ref.: P3751	5/8/13	13/889,655	METHOD OF OPTIMIZING OPTICAL PARAMETRIC MODELS					Pending
81	8536P020Z	FIJI-028; P3751	5/8/12	61/644,147	METHOD OF OPTIMIZING OPTICAL PARAMETRIC MODELS					Expired
82	8536P021	FIJI-031; KLA P3960	10/31/13	14/068,789	METHOD OF CD MEASUREMENT USING MULTILAYER 2D MODELING					Pending
83	8536P021Z	TEL Ref.: FIJI-031; KLA Ref.: P3960	10/31/12	61/720,930	METHOD OF CD MEASUREMENT USING MULTILAYER 2D MODELING					Expired
84	8536P022	FIJI-032; P4082	1/31/14	14/170,150	METHOD OF ELECTROMAGNETIC MODELING OF FINITE STRUCTURES	US-2014-0222380-A1	41858			Pending

					AND FINITE ILLUMINATION FOR METROLOGY AND INSPECTION					
85	8536P022P CT	FIJI-032PCT P4082PCT	2/4/14	PCT/US2014 /014680	METHOD OF ELECTROMAGNETIC MODELING OF FINITE STRUCTURES AND FINITE ILLUMINATION FOR METROLOGY AND INSPECTION	WO 2014/123907	8/14/14			Pending
86	8536P022T W	FIJI-032TW P4082TW	2/5/14	103103831	METHOD OF ELECTROMAGNETIC MODELING OF FINITE STRUCTURES AND FINITE ILLUMINATION FOR METROLOGY AND INSPECTION					Pending
87	8536P022Z	TEL Ref.: FIJI-032; KLA Ref.: P4082	2/5/13	61/761,146	METHOD OF ELECTROMAGNETIC MODELING OF FINITE STRUCTURES AND FINITE ILLUMINATION FOR METROLOGY AND INSPECTION					Expired

88	8536P023	FIJI-034; P3847	6/2/14	14/293,221	DYNAMIC REMOVAL OF CORRELATION OF HIGHLY CORRELATED PARAMETERS FOR OPTICAL METROLOGY					Pending
89	8536P023PCT	FIJI-034PCT; P3847PCT	6/3/14	PCT/US2014/040639	DYNAMICALLY REMOVING CORRELATION OF HIGHLY-CORRELATED PARAMETERS IN OPTICAL METROLOGY					Pending
90	8536P023TW	FIJI-034TW: P3847TW	6/3/14	103119303	DYNAMICALLY REMOVING CORRELATION OF HIGHLY-CORRELATED PARAMETERS IN OPTICAL METROLOGY					Pending
91	8536P023Z	P3847 – FIJI-034	6/3/13	61/830,533	DYNAMICALLY REMOVING CORRELATION OF HIGHLY-CORRELATED PARAMETERS IN OPTICAL					Expired

					METROLOGY					
92	8536P024Z	P3959 – FIJI-033	6/4/13	61/831,080	EFFICIENTLY PARALLELIZABLE METHOD OF CD MEASUREMENT USING MODIFIED T-MATRIX					Expired
93	8536P025	FIJI-038;P4063	6/3/14	14/294,540	OPTIMIZED SPATIAL MODELING FOR OPTICAL CD METROLOGY					Pending
94	8536P025Z	P4063 – FIJI-038	6/3/13	61/830,536	OPTIMIZED SPATIAL MODELING FOR OPTICAL CD METROLOGY					Expired
95	8536P026	FIJI-035;P4069	6/2/14	14/293,625	AUTOMATIC WAVELENGTH AND/OR ANGLE PRUNING FOR MORE ACCURATE OPTICAL METROLOGY					Pending
96	8536P026PCT	FIJI-035PCT; P4069PCT	6/3/14	PCT/US2014/040643	AUTOMATIC WAVELENGTH AND/OR ANGLE PRUNING FOR MORE ACCURATE OPTICAL					Pending

46108235_2

					METROLOGY					
97	8536P026TW	FIJI-035TW; P4069TW	6/3/14	103119304	AUTOMATIC WAVELENGTH AND/OR ANGLE PRUNING FOR MORE ACCURATE OPTICAL METROLOGY					Pending
98	8536P026Z	P4069 – FIJI-035	6/3/13	61/830,543	AUTOMATIC WAVELENGTH AND/OR ANGLE PRUNING FOR MORE ACCURATE OPTICAL METROLOGY					Expired
99	8536P027	FIJI-036P4079	6/2/14	14/293,809	FAST AUTOMATIC DETERMINATION OF FOURIER HARMONIC ORDER FOR RCWA					Pending
100	8536P027PCT	FIJI-036PCT; P4079PCT	6/3/14	PCT/US2014/040644	FAST AUTOMATIC DETERMINATION OF FOURIER HARMONIC ORDER FOR RCWA					Pending
101	8536P027TW	FIJI-036TW: P4079TW	6/3/14	103119307	FAST AUTOMATIC DETERMINATION OF FOURIER					Pending

					HARMONIC ORDER FOR RCWA					
102	8536P027Z	P4079 – FIJI-036	6/4/13	61/831,085	FAST AUTOMATIC DETERMINATION OF FOURIER HARMONIC ORDER FOR RCWA					Expired
103	8536P028Z	P4101 – FIJI-037	6/3/13	61/830,546	LIBRARY GENERATION WITH THE MATCHING SPECTRA TYPE IN CD MEASUREMENTS					Expired
104	8536P029	FIJI-039 & P4189/P4190			RECOMMENDED SAMPLING SHAPE AND AUTO SELECTION OF POPULATED PARAMETER SPACE					Unfiled
105	8536P029Z	FIJI-039; P4189_90	11/15/13	61/904,625	RECOMMENDED SAMPLINGSHAPE AND AUTO SELECTION OF POPULATED PARAMETER SPACE					Pending

46108235_2

46108235_2